

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re Application of:

Seiichiro TACHIBANA et al.

Confirmation No.: 3891

Serial No.: 10/611,853

Examiner:

Unknown

Filed:

July 3, 2003

Group Art Unit:

1753

Title:

ETHER, POLYMER RESIST COMPOSITION AND PATTERNING PROCESS

PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Prior to initial examination, please amend the above-identified application as follows.

Amendments and/or additions to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.